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Applicant
 Dan Meisburger, et al.

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 2878

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
len	A 5 2 8 8 3 6 8	2/22/94	DeMarco et al.	156	643	
len	B 4 6 6 5 3 1 5	5/12/87	Bacchetti et al.	250	492.1	

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Document Number	Date	Country	Class	Subclass	Translation
					Yes No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

len	C	Joy, David C. and Joy, Carolyn S., "Dynamic Charging in the Low Voltage SEM", Microscopy Society of America, 1995, Vol. 1, No. 3, pp. 109-112
len	D	Blais, Phillip D., "Electron-Beam, X-Ray, & Ion-Beam Techniques for Submicrometer Lithographies V", SPIE-The International Society for Optical Engineering, March 11-12, 1986, Vol. 632, pp. 203-209
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len	G	Veneklasen, Lee H., "The Continuing Development of Low-Energy Electron Microscopy for Characterizing Surfaces", Review of Scientific Instruments, Vol. 63, No. 12, December 1992, pp. 5513-5532

EXAMINER
 len. M. V. Yen

DATE CONSIDERED
 03-05-01

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